

OK to
enter
BT

61

AF 1700
PATENT



RECEIVED
OCT 16 2003
TC 1700

IN THE UNITED STATES PATENT OFFICE

In re application of:
David S. Pecora

Serial No.: 09/854,206

Filed: May 11, 2001

**For: ETCH OF SILICON NITRIDE SELECTIVE
TO SILICON AND SILICON DIOXIDE
USEFUL DURING THE FORMATION OF A
SEMICONDUCTOR DEVICE**

§
§ Group Art Unit: 1765 ✓
§
§ Examiner: Binh X. Tran
§
§ Atty. Docket: 00-0737.00/US
§
§ Paper No. 12
§
§
§

Mail Stop AF
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Certificate of Mailing (37 CFR §1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to:
Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450, on the date below:

October 8, 2003
Date

[Signature]
Signature

RESPONSE TO THE FINAL OFFICE ACTION OF JULY 8, 2003

Please enter the following in response to the Examiner's final office action mailed July 8, 2003 as paper no. 11.

Micron Technology, Inc.

00-0737.00/US